

NATIONAL

ACCELERATOR

LABORATORY

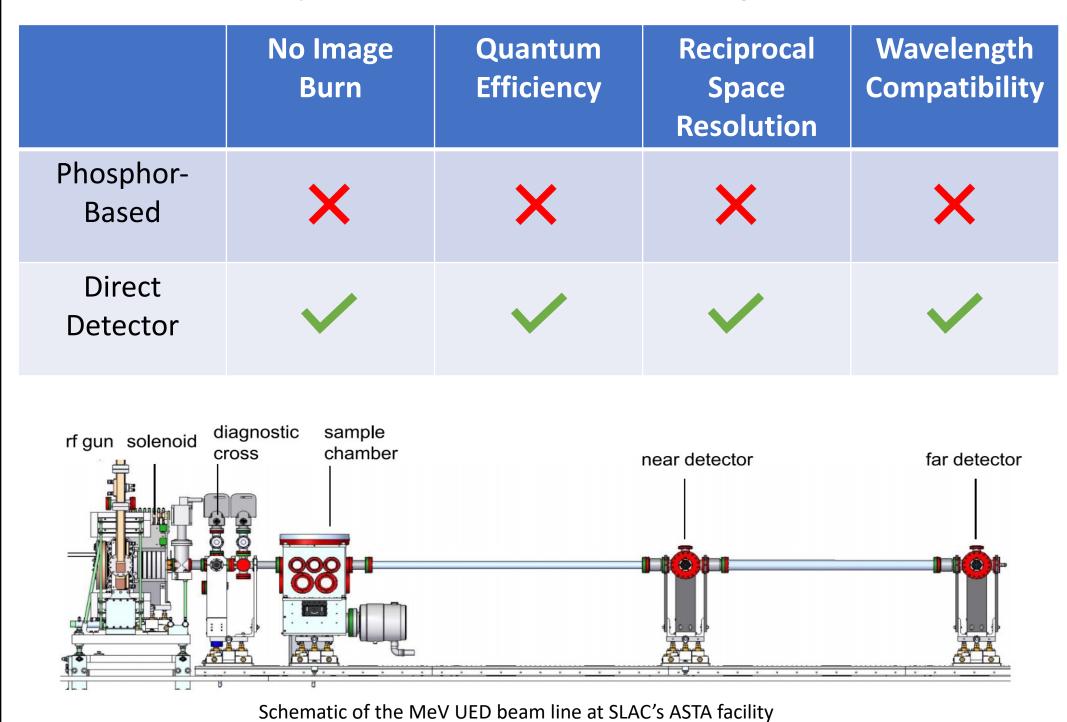
Imaging System

Mega Electron-Volt UED

• Performance increased using MeV sources, MeV UED developed at SLAC

• Beam recorded by two detectors

- . P43 phosphor screen & Andor iXon Ultra 888 EMCCD
- 2. ePIX detector direct electron detecting



AMI-II: Direct Detector Data Analysis Jessica Flowers

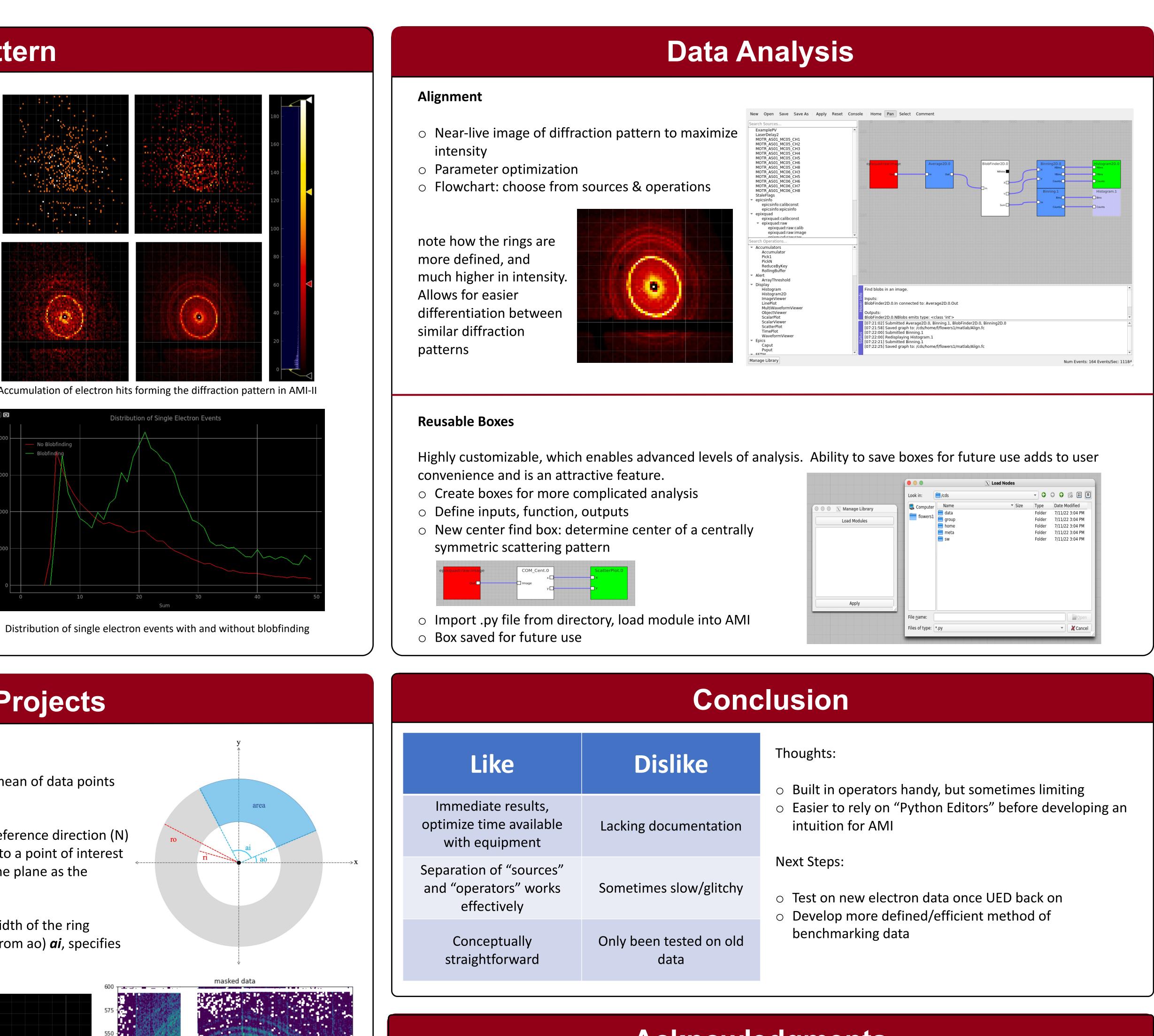
Diffraction Pattern

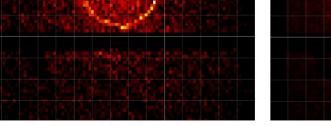
Blobfinding

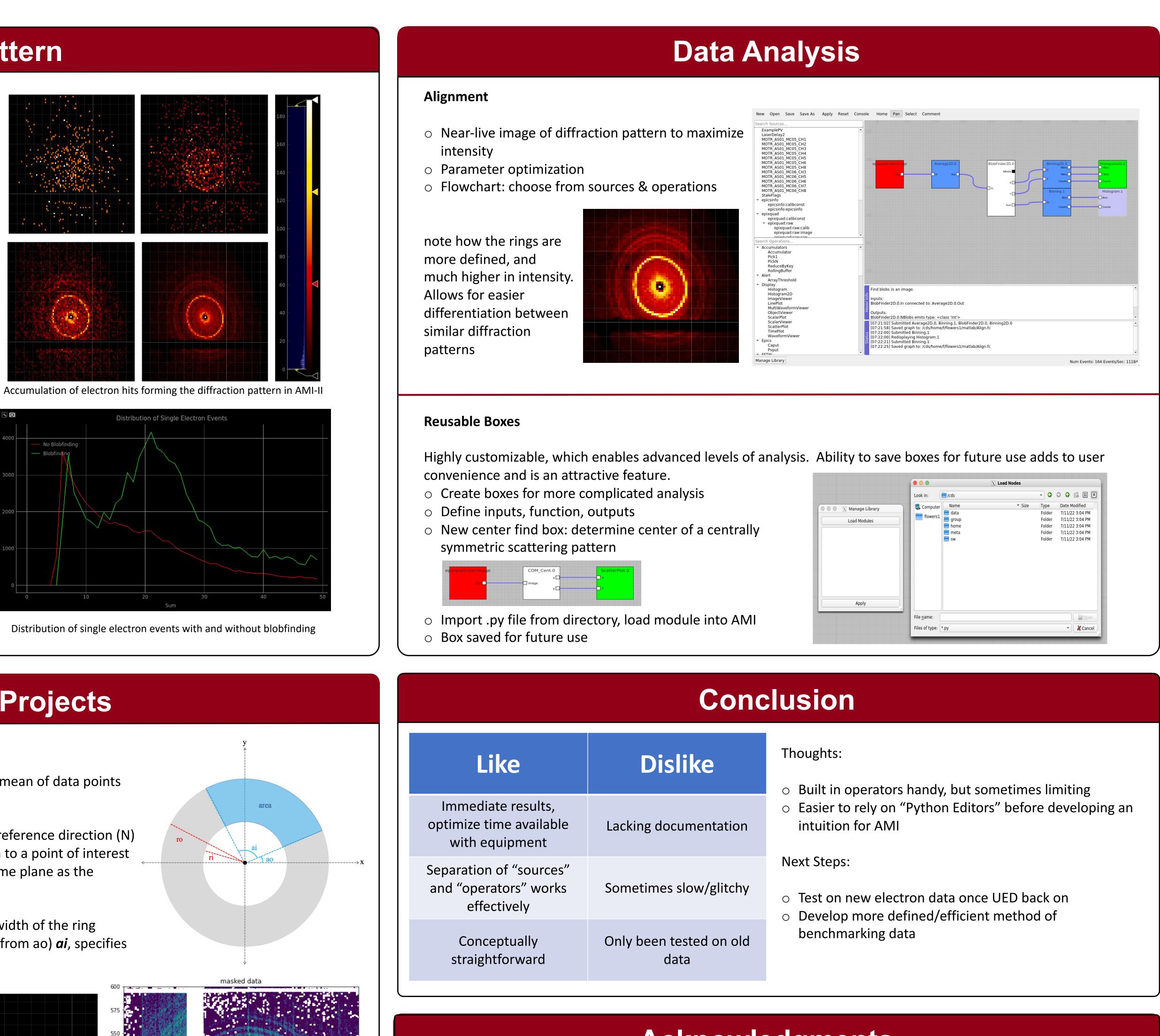
- Optimize experimental parameters, camera diagnostics
- Electron hits should be observed in no less than 4 pixels
- Sum of clusters fit to Landu distribution
 - 1. Locate single pixels exceeding threshold
 - 2. Sum cluster values, must exceed acceptance threshold
 - 3. Plot coordinates/intensity of clusters to visualize diffraction pattern
 - 4. Plot histogram of electron counts against sum

Single Pixel Filtering

- Analyze un-clustered pixels
- Reject pixels below threshold
- Continuous distribution with a small bump due to the electron signal
- Lacks additional filter placed on events from blobfinding
 - Counts must exceed threshold \rightarrow noisy pixels excluded
 - 2. High intensity adjacent pixels must exist such that sum exceeds another threshold \rightarrow events in 2+ pixels counted once



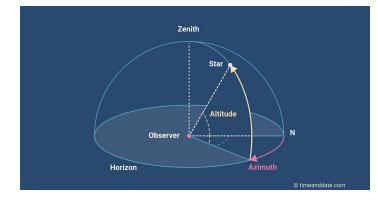




Future Projects

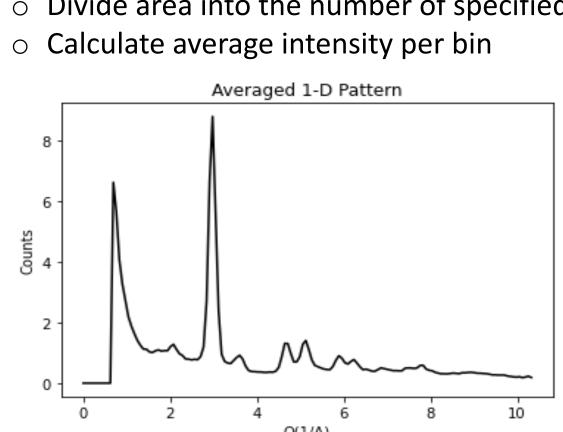
Radial/Azimuthal Integration (RoiArch):

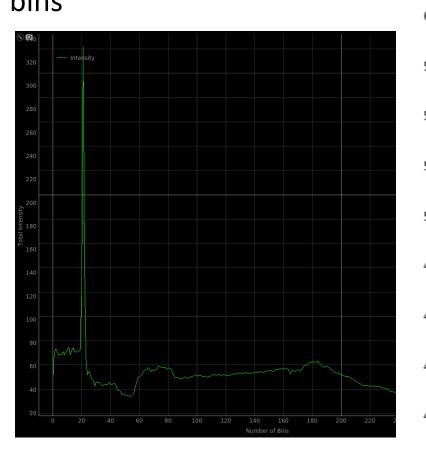
Calculate the circular azimuthal average -- the arithmetic mean of data points located around an azimuth



Azimuth: Angle between a reference direction (N) and a vector from the origin to a point of interest (star) projected onto the same plane as the reference direction.

- Input inner radius *ri* and outer radius *ro* to define the width of the ring
- Input starting angle (from x-axis) *ao* and ending angle (from ao) *ai*, specifies the arc area between the two concentric circles
- Divide area into the number of specified bins







500

550

450

Mentor: Alexander Reid, MeV-UED Instrument Lead Scientist

Group: MeV-UED

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Acknowledgments

